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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
Chen et al.

Serial No. 10/712,460

Filed: 11/13/2003

For: Semiconductor Wafer
Manufacturing Methods
Employing Cleaning Delay Period

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Group Art Unit: 1746

Examiner: To be determined

Customer No.: 000042717

Attorney Docket No.:
TSMC2002-1015/24061.42

TRANSMITTAL

Mail Stop Amendment
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed are the following for filing in the above-identified patent application:

1. Preliminary Amendment (3 pages);
2. Second Information Disclosure Statement (1 page);
3. PTO-1449 Form with copy of cited reference; and
4. a return postcard.

The Commissioner is hereby authorized to charge any fee deficiencies or credit any over payment to the Deposit Account of Haynes and Boone, LLP 08-1394. This form submitted in duplicate.

Respectfully submitted,

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Date: 10-7-04
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Certificate of Mailing I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450 <u>10-7-04</u> Date <u>Bonnie Boyle</u> Bonnie E. Boyle
